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XU-RC350D-C03 (M201V) Manipulator Specification (With Vacuum End-Effector)

NOTE	COPIES CUSTOMER	ENG. Technology Development Section 2 Semiconductor Robot Plant Semiconductor Robotics Division
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Revision History

Document	No.	Document Name	Revised	Approved
HU0481031		Clean Manipulator Specification		
Date	Rev.#	Contents		
Dec.27.'07	1	Page 4:Change the description of "Payload" Page 4,5:Add the item of "EE and Wafer Moment of Inertia" Page 6: Add Chapter 12.Information.		

Application

This document describes the specifications of the clean manipulator with Vacuum End-Effector. Outline drawing: HU0380705.

1. Basic Configuration

The manipulator is capable of: extending arm (R axis), arm rotation (θ axis) and arm elevation (Z axis).

- (1) arm extension -extends and retracts the arm
- (2) arm rotation
 - -rotates the arm
- (3) arm elevation

-moves the arm vertically -prevents the drop by the Brake in the motor, in power failure.



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Mechanical Specifications Basic specifications are shown in the table below.

Item		Specifications	
Payload (End-effector (Note(3)) \pm wafer / each wrist)			
		1.0 Kg	
End-effector + Wafer Moment of Inertia (Note(4))		5.5x10 ⁻² kg/m ²	
Range of Motion	R-axis (extension)	657 mm (reach) Note(1)	
	θ -axis (rotation)	360 deg	
	Z-axis (elevation)	380 mm	
Repeatability	R-axis (extension)		
(300 times measured)	θ -axis (rotation)	p-p 0.1mm	
	Z-axis (elevation)		
Maximum Speed	R-axis (extension)	250deg/sec=1467mm/sec (0.18sec)	
(Acceleration	θ-axis (rotation)	330deg/sec (0.2sec)	
/Deceleration time)	Z-axis (elevation)	300mm/sec (0.2sec)	
Minimum ro	tation diameter	510 mm	
Path Trajectory (side to side)	Individual Axis	±1.0mm	
	Relative path between 2 arm	±0.3mm	
Wafer Transfer Surface	Individual Axis	p-p1.0mm	
Level	Relative level between	p-p0.8mm	
(With 300mm Wafer)	2 arm at full stroke	r r ···	
Clean Class		ISO Class1 Note(2)	
		with 0.2m/s down-flow	
Motor Type		AC200V with 16 bit Absolute Encoder	
		Z-axis: Brake in the motor	
Vacuum Requirement		-80 to -70kPa (-11.6 to -10.2PSI), 22L/min	
Position detection		Absolute encoder for R, θ and Z axis	
		Backup battery for encoder is built into the	
		manipulator	
Approximate mass		Robot: 45 kg	

Note (1): Reach is based on the dimension shown below.



Note (2): Measured in our Clean bench.



2. Exterior

Anodized alminum or Brushed SS.

3. Pneumatically powered Line

The pneumatically powered line is located on the inside of the manipulator.

- The coupling used to provide air is located at the Manipulator connector panel.
- For each wafer clamp line a solenoid valve is provided.

4. Operating & Storage Environments

Operating environment

Temperature:20 ~ 30 °CHumidity:35 ~ 55 % RH (non-condensing)

Storage environment

Temperature: 0 ~ 40 °C Humidity: 20 ~ 80 % RH (non-condensing)

5. Mounting Requirements

See outline drawing.

6. Maintenance

Refer to the Operator Manual and Maintenance Manual

7. Packaging

Collectively packaged and shipped.

8. End-Effector Mapping Sensor

Mapping Sensor is installed on the Manipulator. See Outline drawing.

9. External Cables

Need Encoder Cable and Power Cable. The pair of Encoder cable and Power cable are registered as a part number shown below. (Each Encoder and Power cable is also registered separately. See the drawing.)

	Part number	Cable length (mm)
Cable set	HU0480512-*	Depends on [*]

10. Wafer

Be able to transfer 200mm/300mm Wafer. Mapping of Orientation flat wafer is not supported.

11. Warranty

The warranty shall be as follows.

(1) Range of warranty

Manipulator

(2) Terms

One year after delivery of the product to the END USER, or 18 months after the shipment from YASKAWA factory, whichever comes first.

(3) Details

If defects in design, material, or workmanship occur within the term of the warranty, the defective part will be replaced with a similar item or repaired free of charge. In this case, upon request, YASKAWA will send an engineer to your company or the END USER if necessary.

This warranty shall cover YASKAWA products only. It does not apply to secondary damage as a result of the customers or END USER's product failure.

(4) Exceptions

The following cases shall not be covered even if a product is still under warranty.

- If defects occur as a result of not conducting maintenance or inspection as described in the maintenance manual.
- If defects occur as a result of improper repair, modification, transportation or carelessness in handling by your company or the END USER.
- · If defects occur as a result of acts of Nature such as a fire, flood, earthquake, lightening, etc.

12. Information

(1) Full stroke operation time

Axis	Full stroke	Operation time
R	555mm	0.94sec
θ	360°	1.61sec
Z	380mm	1.78sec